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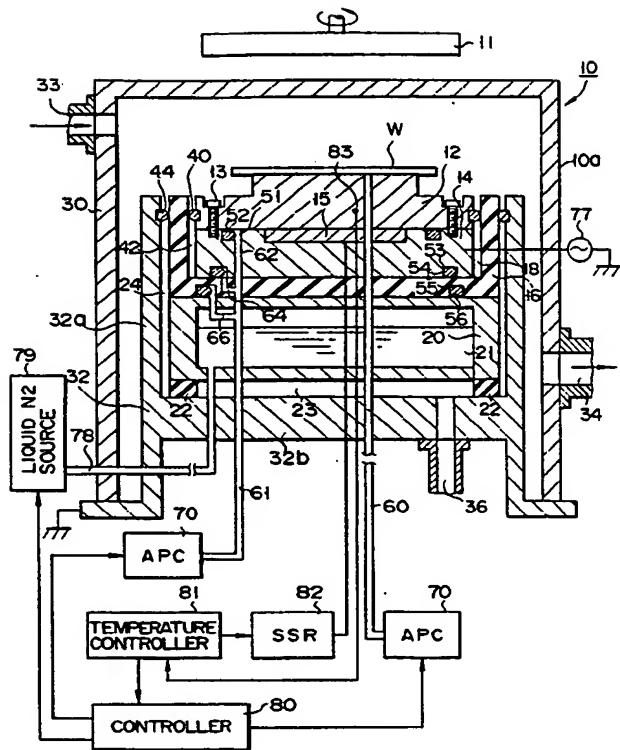
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⑯ Plasma etching apparatus.

⑰ A plasma etching apparatus comprising a susceptor (12, 14) for holding a semiconductive wafer, a cooling jacket (20) having a coolant (21) of a large cooling capacity and capable of quickly cooling said susceptor (12, 14) to an intended low temperature, a process chamber (10a) enclosing the susceptor (12, 14) and the cooling jacket (20), a gas discharging mechanism (34, 36) for evacuating the process chamber (10a), an insulating member (16) inter-

posed between the susceptor (12, 14) and the cooling jacket (20), a gas supply device (71, 80) for supplying gas to an O-ring holding groove (51, 53, 55) arranged on the interface regions (59) of the susceptor (12, 14), the insulating member (16) and the cooling section (20) and a pressure control mechanism (70) for controlling the pressure of the supplied gas.

EP 0 488 307 A3



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EUROPEAN SEARCH REPORT

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DOCUMENTS CONSIDERED TO BE RELEVANT			CLASSIFICATION OF THE APPLICATION (Int. Cl.5)
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	
A	DATABASE WPIL Week 8949, Derwent Publications Ltd., London, GB; AN 89-359386 & JP-A-1 268 030 (HITACHI) * abstract * & US-A-5 085 750 (SORAOKA) * column 3, line 19 - column 4, line 48; figure 1 * ---- EP-A-0 339 580 (APPLIED MATERIALS INC) * column 16, line 9 - column 18, line 5; figure 7 * -----	1, 2 1	H01J37/32 H01L21/00
			TECHNICAL FIELDS SEARCHED (Int. Cl.5)
			H01L H01J
<p>The present search report has been drawn up for all claims</p>			
Place of search	Date of completion of the search	Examiner	
THE HAGUE	28 SEPTEMBER 1992	BOLDER G.	
CATEGORY OF CITED DOCUMENTS		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons A : member of the same patent family, corresponding document	
X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document			